Segmented MEMS Mirror Arrays

Mirror Technology Days 2006 Kirtland AFB

NASA Phase II SBIR Contract # NNC05CA21C



Agenda

- Umachines background
- High level approach
- Device results



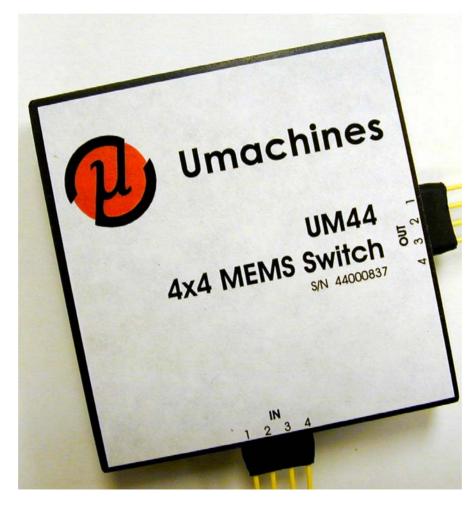
Umachines History

- 1997 1999: flow sensors
- 1999 2003: optical switch for telecom
- 2003 2006: adaptive optics

- Capabilities:
 - Design, Fabrication (Caltech/UCLA), Test
- Outsource:
 - Mechanical Packaging, Electronics



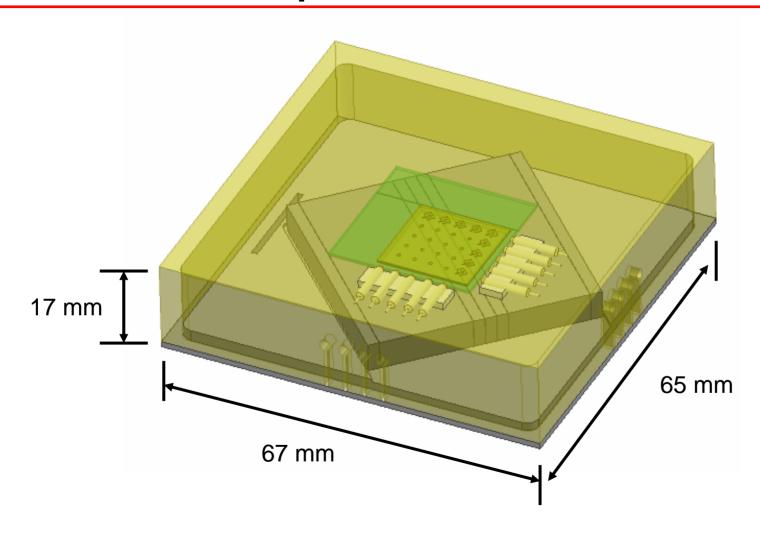
Optical Switch





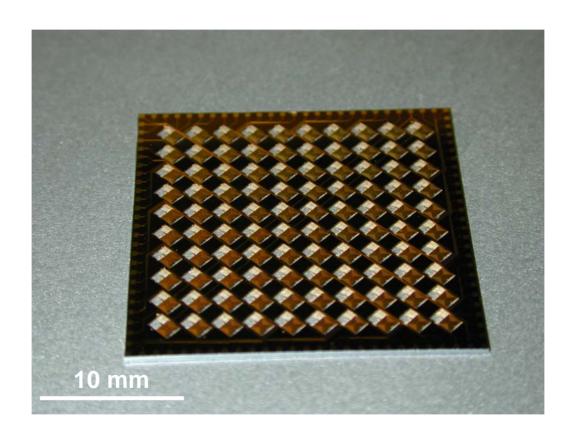
NASA Mirror Technology Days

Optical Switch





Optical Switch Pictures





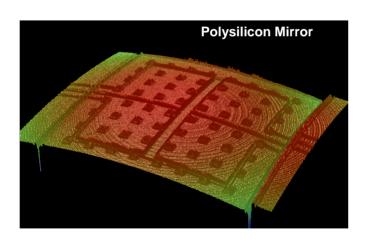
Optical Switch

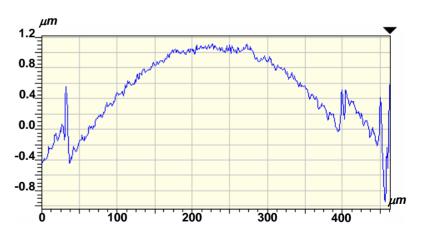
- VC funded effort
 - Takes a lot of \$\$\$ to develop a product
- Greatest technical accomplishment
 - Telcordia qualification difference between lab curiosity and product
- Many technical lessons learned
 - Can be applied to other optical MEMS devices



Switch -> Mirror

- Single crystal vs polysilicon for mirror structural material (Wu, Su - UCLA)
 - Competitor lesson







Switch -> Mirror

- Design for reliability
 - If the MEMS can take the pressure…
 - Thermal symmetry



Switch -> Mirror

- Design for manufacturing
 - IC cost structure is often used as example, but volumes are required
 - If MEMS are mass produced, but packaging is serial, big problem



Lesson Applications

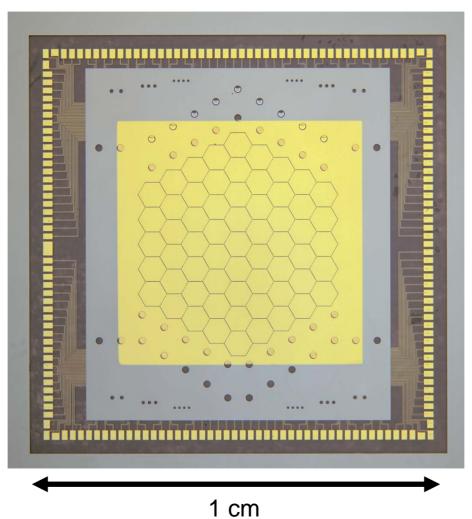
- Use single crystal silicon as mirror material
- Use symmetric mechanical designs wherever possible
- Design for packaging (think about electrical leads required for large port count devices)



Current Results

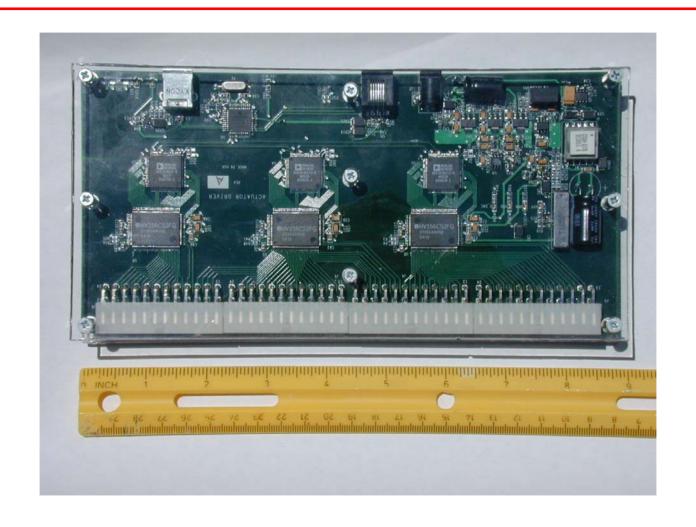


61 Element Array



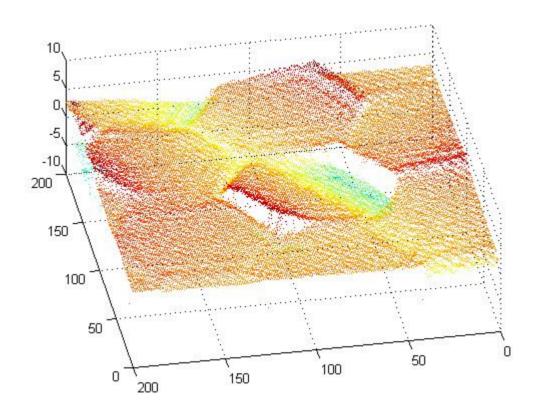


80-Ch Driver





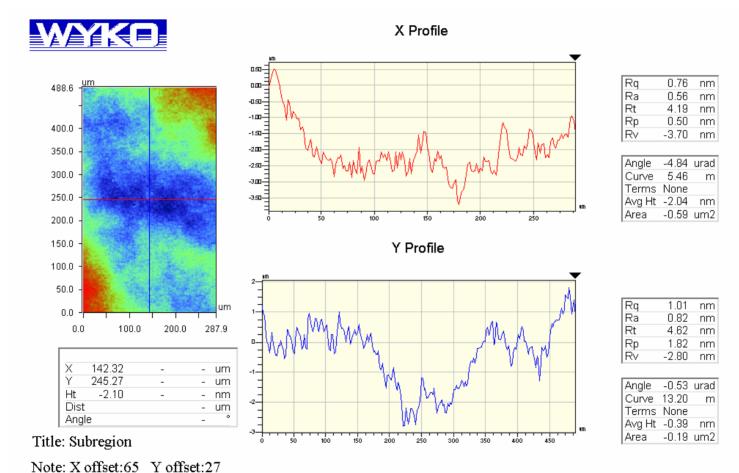
Optical Results



4-bin PSI Image (Mansell)

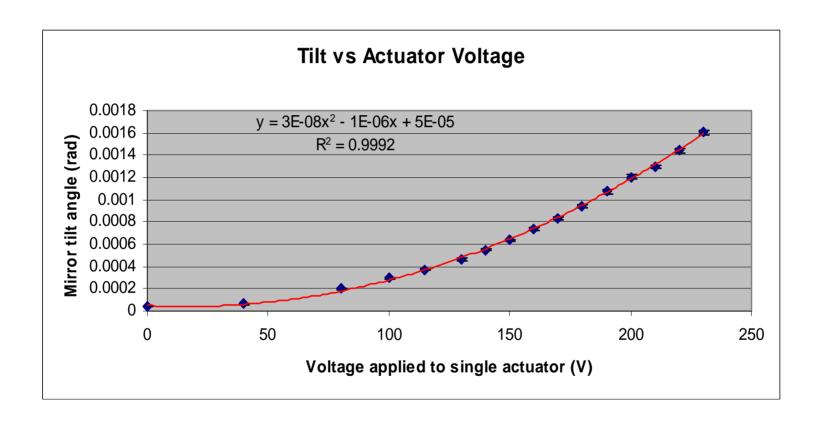


Surface Quality



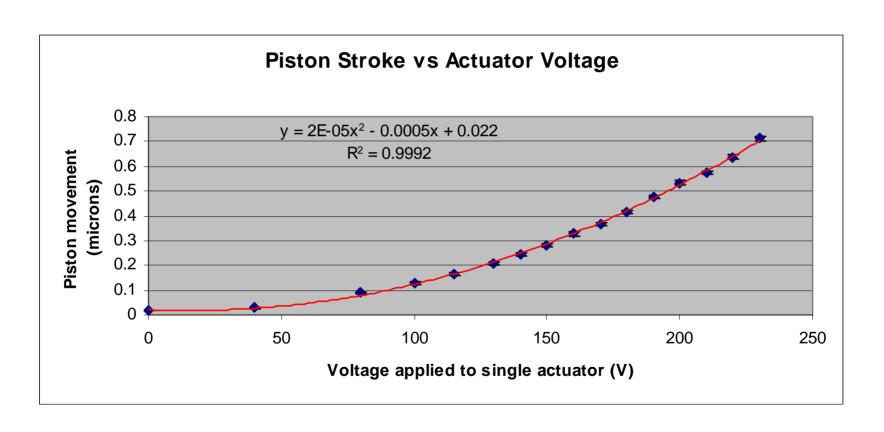


Mechanical Test Results





Mechanical Test Results





Continuous Membrane Simulation

Displacement along A-A

